

# ISO 14997:2003-04 (E)

## Optics and optical instruments - Test methods for surface imperfections of optical elements

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<b>Contents</b>		<b>Page</b>
Foreword .....		iv
Introduction .....		v
<b>1</b>	<b>Scope .....</b>	<b>1</b>
<b>2</b>	<b>Normative references .....</b>	<b>1</b>
<b>3</b>	<b>Terms and definitions .....</b>	<b>1</b>
<b>4</b>	<b>Physical principles .....</b>	<b>2</b>
<b>5</b>	<b>Method I: Measurement of obscured or affected area .....</b>	<b>3</b>
<b>5.1</b>	<b>General .....</b>	<b>3</b>
<b>5.2</b>	<b>Requirements .....</b>	<b>3</b>
<b>5.3</b>	<b>Calibration .....</b>	<b>4</b>
<b>5.4</b>	<b>Procedure .....</b>	<b>4</b>
<b>5.5</b>	<b>Test report .....</b>	<b>5</b>
<b>6</b>	<b>Method II: Measurement of visibility .....</b>	<b>6</b>
<b>6.1</b>	<b>General .....</b>	<b>6</b>
<b>6.2</b>	<b>Calibration .....</b>	<b>6</b>
<b>6.3</b>	<b>Procedure .....</b>	<b>6</b>
<b>6.4</b>	<b>Test report .....</b>	<b>6</b>
	<b>Annex A (informative) Component inspection for Method I .....</b>	<b>8</b>
	<b>Annex B (informative) Recommended dimensions of artefacts on a scale comparison plate for Method I .....</b>	<b>9</b>
	<b>Annex C (informative) Description of the instrument used for measuring imperfections below 0,01 mm: Microscope image comparator (Method I) .....</b>	<b>10</b>
	<b>Annex D (informative) Imperfection quality control .....</b>	<b>13</b>
	<b>Annex E (informative) Inspection station (Method II) .....</b>	<b>15</b>
	<b>Bibliography .....</b>	<b>20</b>